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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application

Inventor(s): Fan Zhong and Jonathan G. Bornstein Group Art
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Examiner:

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Serial No.: 09/874,434

TC 1700

Title: METHOD AND SYSTEM FOR A HIGH-DENSITY PLASMA DEPOSITION PROCESS FOR
FABRICATING A TOP CLAD FOR PLANAR LIGHTWAVE CIRCUIT DEVICES

Form 1449

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
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Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation Yes	No
	L							
	M							
	N							
	O							
	P							
	Q							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication	Date Considered
	R		
	S		
	T		

Examiner: *Tec A. Fortuna* Date Considered: *7/9/03*Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered.
Include copy of this form with next communication to applicant.